

FORM PTO-1449 (Modified)		Attorney Docket No.: A524R1/T289		Application No.: 09/187,551	
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		Applicant: MUSAKA et al.			
		Filing Date: November 5, 1998		Group: 1762	
Reference Designation		U.S. PATENT DOCUMENTS			Page 1
Examiner Initial	Document No.	Date	Name	Class	Filing Date (If Appropriate)
<i>AA</i>	5,483,636	01/09/96	Saxena	395	03/29/95
<i>AB</i>	5,750,211	05/12/98	Weise et al.	427	07/16/93

FOREIGN PATENT DOCUMENTS						
	Document No.	Date	Country	Class	Sub-class	Translation (Yes/No)
<i>AC</i>	0 666 340 A1	08/09/95	EP	C23C 16/44	C23C 16/52	in English Yes
<i>AD</i>	0 724 286 A1	07/31/96	EP	H01L 21/316	C23C 16/40	in English Yes
<i>AE</i>	07-29975	01/31/95	JP	H01L 21/768	H01L 21/205	Yes (abstract)
OTHER ART (Including Abstracts, Title, Date, Pertinent Pages, Etc.)						
<i>AF</i>	Bazylenko, M.V. et al., "Pure And Fluorine-Doped Silica Films Deposited In A Hollow Cathode Reactor For Integrated Optic Applications", <i>J. Vac. Sci. Technol. A</i> 14(2), Mar/Apr 1996, pp. 336-345.					
<i>AG</i>	Mizuno et al., "Dielectric Constant and Stability of Fluorine Doped PECVD Silicon Oxide Thin Films", <i>Thin Solid Films</i> 283 (1996) pp. 30-36. <i>Sept.</i>					
EXAMINER	<i>[Signature]</i>		DATE CONSIDERED	3/15/00		

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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